

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Gaku MINAMIHABA et al.) Parent Group Art Unit: 2812
)
Application No.: 1.53(b) Divisional of) Parent Examiner: Gurley, Lynne Ann
Application No. 10/303,855, filed)
November 26, 2002)
)
Application No.: To be Assigned)
)
Filed: Herewith)
)
For: SLURRY FOR CHEMICAL)
MECHANICAL POLISHING OF)
COPPER AND METHOD OF)
MANUFACTURING A)
SEMICONDUCTOR DEVICE)
USING THE SLURRY)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

PRELIMINARY AMENDMENT

Prior to the examination of the above application, please amend this application
as follows:

Amendments to the Specification begin on page 3 of this paper.

An Amendment to the Abstract is provided on page 6 of this paper and on a
separate page enclosed herewith.

Amendments to the Claims begin on page 7 of this paper.

Remarks begin on page 10 of this paper.

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Attachments to this amendment include an amended Abstract.

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